Takaki YOSHIDA et al Serial No.: 09/697,305

## IN THE CLAIMS:

1-4 (Canceled)

5. (Currently Amended) The A fault detecting method for a semiconductor integrated circuit according to claim 3, additionally comprising:

providing a fault list comprising information identifying physical sites on a physical layout of a semiconductor integrated circuit where a possible fault is likely to occur, and information related to reducing faults;

detecting faults in accordance with the fault list in a semiconductor integrated circuit to which said fault list corresponds;

weighting possible faults at physical sites according to their likelihood to achieve a specific fault coverage, thereby creating weighted possible faults;

providing fault coverage by identifying a fault coverage value from the sum of the weighted fault coverage of detected weighted possible faults,

wherein said fault list is a weighted fault list with respect to all faults listed therein, and said fault coverage is a rate of fault coverage detected by the weighted fault list.

6. (Previously Presented) The fault detecting method for a semiconductor integrated circuit according to claim 5, additionally comprising arranging said possible faults as ordered possible faults and then weighting said ordered possible faults.

Takaki YOSHIDA et al Serial No.: 09/697,305

7. (Currently Amended) The fault detecting method for a semiconductor integrated circuit according to claim [4] 8, additionally comprising obtaining mask information from a layout device for laying out a semiconductor integrated circuit to which the fault list corresponds, wherein said order of possible faults is based on the mask information.

8. (Previously Presented) A fault detecting method for a semiconductor integrated circuit comprising:

providing a fault list comprising (a) information identifying physical sites on a physical layout of a semiconductor integrated circuit where a possible fault is likely to occur, and (b) information required to reduce faults;

detecting faults in accordance with said fault list in a semiconductor integrated circuit to which said fault list corresponds;

calculating a density of a mask pattern corresponding to mask information obtained from a layout device for laying out the semiconductor integrated circuit to which said fault list corresponds;

calculating a likelihood of occurrence for each possible fault depending on the density of the mask pattern;

weighting the arranged possible faults according to said calculated likelihoods of occurrence;

arranging the possible faults in the fault list in order according to their likelihood of occurrence to create an ordered fault list; and

detecting faults in said semiconductor integrated circuit by using the ordered fault list,

wherein the fault list comprises data about a likelihood of a fault occurring at a physical site.

9. (Currently Amended) The fault detecting method for a semiconductor integrated circuit according to claim [4] 8, additionally comprising:

considering reliability data based on records of past use of cells or functional blocks of a semiconductor integrated circuit to which the fault list corresponds; and

determining said likelihoods of occurrence of defects based on said reliability data.

10. (Previously Presented) The fault detecting method for a semiconductor integrated circuit according to claim 6, additionally comprising:

defining a required fault list by deleting from the fault list possible faults that are not required to achieve a specified fault coverage, in an order of unlikelihood of such possible faults, said specific fault coverage being a probability of detecting faults in a semiconductor integrated circuit to which said fault list corresponds; and

detecting, according to said required fault list, remaining faults in such semiconductor integrated circuit; and

calculating a fault coverage simultaneously with said detecting.

11. (Previously Presented) The fault detecting method for a semiconductor integrated circuit according to claim 6, additionally comprising:

calculating fault coverage simultaneously with detecting possible faults in such semiconductor integrated circuit; and

Takaki YOSHIDA et al Serial No.: 09/697,305

terminating calculating and detecting when a specific fault coverage has been reached, said specific fault coverage being a probability of detecting faults in such semiconductor integrated circuit.

12. (Canceled)

13. (Currently Amended) The fault detecting method for a semiconductor integrated circuit according to claim 12 19, additionally comprising:

omitting from the fault list possible faults having a specified low probability of occurrence to define a remaining part of the fault list, wherein

said again detecting faults comprises detecting faults according to the remaining part of the fault list.

Claims 14-18 (Canceled)

19. (Previously Presented) A fault detecting method for a semiconductor integrated circuit comprising:

first detecting faults in a semiconductor integrated circuit to create a detection result;

combining said detection result with (a) information about physical sites on a physical
layout of the semiconductor integrated circuit to which said fault list corresponds where a

possible fault is likely to occur and (b) information required to reduce faults, to create a fault list;

again detecting faults according to said fault list in such semiconductor integrated circuit;

Serial No.: 09/697,305

calculating a density of a mask pattern corresponding to mask information obtained from

a layout device for laying out the semiconductor integrated circuit to which said fault list

corresponds;

calculating a likelihood of occurrence for each possible fault depending on the density of

the mask pattern;

weighting the arranged possible faults according to said calculated likelihoods of

occurrence;

arranging the possible faults in order according to their likelihood of occurrence to create

an ordered fault list; and

second detecting possible faults in a semiconductor integrated circuit using the ordered

fault list,

wherein the fault list comprises data about a likelihood of a possible fault occurring at a

physical site.

20. (Currently Amended) The fault detecting method for a semiconductor integrated

circuit according to claim 15 19, further comprising:

providing a database and storing therein reliability data based on records of past use of

cells or functional blocks of a semiconductor integrated circuit to which the fault list

corresponds; wherein

said likelihoods of occurrence are according to said reliability data in the database.

Claims 21-59 (Canceled)

-6-